

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:** Nathan R. Brown

**Serial No.:** 10/715,267

**Filed:** November 17, 2003

**For:** METHODS FOR POLISHING  
SEMICONDUCTOR DEVICE  
STRUCTURES BY DIFFERENTIALLY  
APPLYING PRESSURE TO SUBSTRATES  
THAT CARRY THE SEMICONDUCTOR  
DEVICE STRUCTURES

**Confirmation No.:** 4590

**Examiner:** S. Macarthur

**Group Art Unit:** 1792

**Attorney Docket No.:** 2269-4375.1US  
(1999-1029.01/US)

VIA ELECTRONIC FILING  
January 25, 2010

**AMENDMENT UNDER 37 C.F.R. §1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Examiner:

This Amendment follows the final Office Action of November 25, 2009, the shortened statutory period for response to which expires on February 25, 2010. This Amendment is being submitted within two months of the date on which the final Office Action was mailed.

An amendment to the specification appears on page 2 of this paper;

A listing of claims, in which amendments to the claims are presented, begins on page 3 of this paper; and

Remarks start at page 8 of this paper.